Materials Science and Engineering
University of Florida

MAIC Current Listing of Facilities

Instrument	Description/Capabilities
Focused Ion-Beam Dual-Beam Strata DB235	Sample preparation for Transmission Electron Microscopy.
FEI XL-40 FEG-SEM	Field Emission Gun Scanning Electron Microscope
JEOL SEM-6400 (2 Units)	Scanning Electron Microscope, SEI, BEI, EDS, EBSD, CLD
Nanometer Pattern Generation System (NPGS)	E-beam Lithography system coupled to the XL-40
Hysitron TriboIndenter:	Nano mechanical Testing system
JEOL 2010F	Field Emission Scanning Transmission Electron Microscope/ TEM STEM-Z, EDS, EELS, Remote Operation Capabilities
JEOL 200CX	Analytical Electron Microscope/ TEM, STEM, Digital Imaging and EDS INCA 200 System
JEOL 6335F	Field Emission Scanning Electron Microscope/ SEI, BEI, EDS, Remote Operation Capabilities
JEOL Superprobe 733	Electron Microprobe/ EDS, WDS, SEI, BEI
KRATOS XSAM 800	Analytical Surface Analyzer/ AUGER, XPS
Perkin Elmer 5100 XPS System	X-Ray Photoelectron Spectrometer/ XPS/ESCA, ARXPS
Perkin-Elmer PHI 660	Scanning Auger Multiprobe/ AES, SEI
Philips APD 3720 (2 Units)	X-Ray Diffractometer
Philips HT APD 3720	High Temperature X-Ray Diffractometer
Philips X'Pert MRD	Materials Research Diffractometer
SPM/AFM Multimode Nanoscope III	Scanning Probe Microscope/ Atomic Force Microscope
SPM/AFM Dimension 3100	Scanning Probe Microscope/ Atomic Force Microscope

Omicron SPM	Ultra High Vacuum Scanning Probe Microscope
FT-IR Nicolet 20 SXB	Fourier Transform Infrared Analyzer
Veeco Wyko NT 1000 Profiler	Optical profilometer
Filmetrics F20	Ellipsometer/ Thin Film Measurement System
Surfometer Series 400	Stylus Profilometer (Precision Devices Inc.)
Leica Ultracut UCT	Ultracryomicrotome
TEM Sample Prep	Ion Mills (3 Units), Dimpler, Ultrasonic Cutter, Grinding and Polishing